

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Hidemitsu Aoki, et al.

Examiner: S. T. Chaudhry

Serial No.: ~~unassigned~~ 10/07SS66

Art Unit: 1746

Filed: ~~herewith~~ 2-13-02

Docket: 12688A

For: METHOD FOR CLEANING
SEMICONDUCTOR WAFER AFTER
CHEMICAL MECHANICAL POLISHING
COPPER WIRING

Dated: February 13, 2002

Assistant Commissioner for Patents
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Applicants submit the following Amendment for entry in the above-identified application.

CERTIFICATE OF MAILING BY EXPRESS MAIL

Express Mail Mailing Label Number EV-010-535-685-US

Date of Deposit: February 13, 2002

I hereby certify that this correspondence is being deposited with the United States Postal Service Express Mail Post Office to Addressee service under 37 C.F.R. §1.10 on the date indicated above and is addressed to the Assistant Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Dated: February 13, 2002


Michelle Mustafa